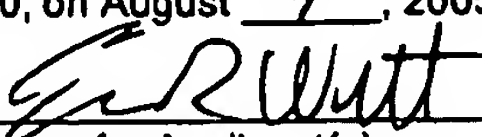


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| CERTIFICATE OF MAILING | |
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| I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Mail Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on August <u>4</u> , 2005. | |
|  Attorney for Applicant(s) | |

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

| | | | |
|--------------|---|--|------------------------|
| Appl. No. | : | 10/631,134 | Confirmation No.: 2470 |
| Applicant | : | Hui-Chu Lin et al. | |
| Title | : | METHOD FOR IMPROVING FILM UNIFORMITY IN PLASMA ENHANCED CHEMICAL VAPOR DEPOSITION SYSTEM | |
| Filed | : | July 31, 2003 | |
| TC/A.U. | : | 1762 | |
| Examiner | : | Eric B. Fuller | |
| Docket No. | : | 3304.2.75 | |
| Customer No. | : | 21552 | |

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AND RESPONSE TO FINAL OFFICE ACTION

Dear Sir:

This paper is filed in response to the Office Action of May 5, 2005. Please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.